IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Ralf LERNER
) Group Art Unit: Not yet assigned
)
Appln. No.: 10/552,984
) Examiner: Not yet assigned
)
I.A. Filed: April 19, 2004
) Confirmation No: 2111

For : TEST STRUCTURE FOR LECT

TEST STRUCTURE FOR LECTRICALLY VERIFYING THE DEPTHS OF

TRENCH-ETCHING IN AN SOI WAFER, AND ASSOCIATED WORKING

METHODS

PRELIMINARY AMENDMENT

Commissioner for Patents
U.S. Patent and Trademark Office
Customer Window, Mail Stop PCT
Randolph Building
401 Dulany Street
Alexandria, VA 22314

Prior to an examination of the above-identified patent application, the Examiner is respectfully requested to amend the claims as follows:

Amendments to the Claims begin on page 2 of this Preliminary Amendment.

Remarks begin on page 9 of this Preliminary Amendment.